#### IN THE CLAIMS:

Please amend claims 36, 39, 40, 44-49 and 51-52; and cancel claims 37-38 and 50, as set forth below:

- 1-35. (Canceled)
- (Currently amended) A pFET synapse transistor, comprising:

a readout transistor for injecting electrons into a floating gate, the readout transistor comprising:

- a p- doped substrate including: [[;]]
  - a first n- well and a second n- well disposed in said p-doped substrate:
  - a first p+ doped region disposed in said first n- well forming a first source; and
  - a second p+ doped region disposed in said first n- well forming a <u>first</u> drain, a <u>number of electrons injected into the floating</u> gate increased responsive to increase in a voltage difference between the first source and the first drain; and
  - a channel disposed in said first n- well between said source and said drain:
- a first layer of gate oxide above said channel and said first n- well; and
  a first polysilicon floating gate disposed above said layer of gate oxide; and
  a shorted transistor for removing electrons from the floating gate, the shorted
  transistor comprising:

a p- doped substrate including a second n-well, a second drain within the second n-well, and a second source within the second n-well:

a second layer of gate oxide above said first n- well;

a second polysilicon floating gate above said second layer of gate oxide, the second polysilicon floating gate connected to the first polysilicon floating gate; and a conductor connecting the second drain and the second source, a number of electrons removed from the second polysilicon floating gate increase responsive to

electrons removed from the second polysilicon floating gate increase responsive to increase in voltage at the second drain or the second source.

a third p+ doped region and a fourth p+ doped region disposed in said second n-well, said third p+ doped region and said fourth p+ doped region together forming a tunneling junction;

a layer of gate exide disposed above said channel, said first n-well and said second nwell;

a polysilicon floating gate disposed above said layer of gate oxide; a source contact terminal electrically coupled to said source; a drain contact terminal electrically coupled to said drain; and a well contact terminal electrically coupled to said second n well-

37-38. (Canceled)

- 39. (Currently amended) [[A]] The pFET synapse transistor in accordance with claim 36 elaim 38, wherein said readout transistor and the shorted transistor include transistor is formed with a single layer of conductive polysilicon.
- (Currently amended) [[A]] The pFET synapse transistor in accordance with claim 36 fabricated using a standard CMOS process.

#### 41-43. (Canceled)

44. (Currently amended) A pFET synapse transistor, comprising:

a readout transistor for injecting electrons into a floating gate, the readout transistor comprising:

a p- doped substrate including: [[;]]

a first n- well and a second n-well disposed in said substrate;

a first p+ doped region disposed in said first n- well forming a first source; and-

a second p+ doped region disposed in said first n- well forming a first drain, a number of electrons injected into the floating gate increased responsive to increase in a voltage difference between the first source and the first drain; and

a channel disposed in said first n- well between said source and said drain;

a first layer of gate oxide above said channel and said first n- well; and
a first polysilicon floating gate disposed above said layer of gate oxide; and
a shorted transistor for removing electrons from the floating gate, the shorted

a p- doped substrate including a second n-well, a second drain within the second n-well. and a second source within the second n-well:

a second layer of gate oxide above said first n- well;

a second polysilicon floating gate above said second layer of gate oxide, the second polysilicon floating gate connected to the first polysilicon floating gate;

transistor comprising:

a conductor connecting the second drain and the second source, a number of electrons removed from the second polysilicon floating gate increased responsive to

increase in voltage at the second drain or the second source; and

a third p+ doped region and a fourth p+ doped region disposed in said second n- well,

a layer of gate oxide disposed above said channel, said first n-well and said second n-well-

a polysilicon floating gate disposed above said layer of gate oxide;

said third p+ region and said fourth p+ region together forming a tunneling junction:

a source contact terminal electrically coupled to said source:

a drain contact terminal electrically coupled to said drain; and

a well contact terminal electrically coupled to said second n- well, wherein said synapse transistor is configured to operate as a current source without gate input using a single polysilicon gate layer.

45. (Currently amended) A system on a chip (SOC) including digital and analog circuits integrated on a single semiconductor chip, the system comprising:

a pFET synapse transistor including:

a readout transistor for injecting electrons into a floating gate, the readout transistor comprising;

a p- doped substrate including;

a first n- well and a second n- well disposed in said p-

doped substrate;

a first p+ doped region disposed in said first n- well

forming a first source; and

a second p+ doped region disposed in said first n- well forming a first drain, a number of electrons injected into the floating gate increased responsive to increase in a voltage difference between the first source and the first drain; and a channel disposed in said first n- well between said source and said drain;

a first layer of gate oxide above said channel and said first n- well; and a first polysilicon floating gate disposed above said layer of gate

### oxide; and

a shorted transistor for removing electrons from the floating gate, the shorted transistor comprising:

a p- doped substrate including a second n-well, a second drain within
the second n-well, and a second source within the second n-well;
a second layer of gate oxide above said first n- well;
a second polysilicon floating gate above said second layer of gate
oxide, the second polysilicon floating gate connected to the first polysilicon
floating gate; and

a conductor connecting the second drain and the second source, a number of electrons removed from the second polysilicon floating gate increased responsive to increase in voltage at the second drain or the second source.

a third p+ doped region and a fourth p+ doped region disposed in said second n- well, said third p+ region and said fourth p+ region together forming a tunneling junction;

- a layer of gate oxide disposed above said channel, said first n- well and said-second nwell:
  - a polysilicon floating gate disposed above said layer of gate oxide;
  - a source contact terminal electrically coupled to said source;
  - a drain contact terminal electrically coupled to said drain; and
  - a well contact terminal electrically coupled to said second n-well.
- 46. (Currently amended) A p-channel floating-gate device, comprising:
- a readout transistor for injecting electrons into a floating gate, the readout transistor comprising:
  - a p- doped substrate including: [[;]]
    - a first n- well and a second n-well disposed in said p-dopedsubstrate;
    - a first p+ doped region disposed in said first n- well forming a first source; and
    - a second p+ doped region disposed in said first n- well forming a <u>first</u> drain, a <u>number of electrons injected into the floating</u> gate increased responsive to increase in a voltage difference between the first source and the first drain; and
    - a channel disposed in said first n- well between said source and said drain:
  - a first layer of gate oxide above said channel and said first n-well; and
    a first polysilicon floating gate disposed above said layer of gate oxide; and

a shorted transistor for removing electrons from the floating gate, the shorted transistor comprising:

a p- doped substrate including a second n-well, a second drain within the second n-well, and a second source within the second n-well;

a second layer of gate oxide above said first n- well;

a second polysilicon floating gate above said second layer of gate oxide, the

second polysilicon floating gate connected to the first polysilicon floating gate; and

a conductor connecting the second drain and the second source, a number of electrons removed from the second polysilicon floating gate increased responsive to

increase in voltage at the second drain or the second source.

a third p+ doped region and a fourth p+ doped region disposed in said second n well, said third p+ region and said fourth p+ region together forming a tunneling junction;

a layer of gate oxide disposed above said channel, said first n—well and said second n—well-

a single polysilicon layer disposed above said layer of gate oxide, said single polysilicon layer comprising a floating gate;

a source contact terminal electrically coupled to said source;

a drain contact terminal electrically coupled to said drain; and

a well contact terminal electrically coupled to said second n- well.

47. (Currently amended) A system on a chip (SOC) including digital and analog circuits integrated on a single semiconductor chip, the system comprising:

a readout transistor for injecting electrons into a floating gate, the readout transistor comprising:

## a p- doped substrate including: [[;]]

- a first n- well and a second n- well disposed in said p-doped substrate:
- a first p+ doped region disposed in said first n- well forming a first source; and
- a second p+ doped region disposed in said first n- well forming a <u>first</u> drain, a <u>number of electrons injected into the floating</u> gate increased responsive to increase in a voltage difference between the first source and the first drain; and
- a channel disposed in said first n- well between said source and said drain:
- a first layer of gate oxide above said channel and said first n- well; and

  a first polysilicon floating gate disposed above said layer of gate oxide; and
  a shorted transistor for removing electrons from the floating gate, the shorted
  transistor comprising;
  - a p- doped substrate including a second n-well, a second drain within the second n-well, and a second source within the second n-well;

a second layer of gate oxide above said first n- well;

a second polysilicon floating gate above said second layer of gate oxide, the second polysilicon floating gate connected to the first polysilicon floating gate; and a conductor connecting the second drain and the second source, a number of electrons removed from the second polysilicon floating gate increased responsive to increase in voltage at the second drain or the second source.

a third p+ doped region and a fourth p+ doped region disposed in said second n—well, said third p+ region and said fourth p+ region together forming a tunneling junction;

a layer of gate oxide disposed above said channel, said first n-well and said second nwell;

a single polysilicon layer disposed above said layer of gate oxide, said single polysilicon layer comprising a floating gate;

- a source contact terminal electrically coupled to said source;

  a drain contact terminal electrically coupled to said drain; and
- a well contact terminal electrically coupled to said second n-well-
- 48. (Currently amended) A p-channel floating gate device comprising:

a readout transistor for injecting electrons into a floating gate, the readout transistor comprising:

# a p- doped substrate including: [[;]]

a first n- well and a second n-well disposed in said p-dopedsubstrate;

a first p+ doped region disposed in said first n- well forming a first source; and

a second p+ doped region disposed in said first n- well forming a first drain, a number of electrons injected into the floating gate increased responsive to increase in a voltage difference between the first source and the first drain; and

a channel disposed in said first n- well between said source and said drain:

a first layer of gate oxide above said channel and said first n- well; and

a first polysilicon floating gate disposed above said layer of gate oxide; and

a shorted transistor for removing electrons from the floating gate, the shorted

transistor comprising:

a p-doped substrate including a second n-well, a second drain within the second n-well, and a second source within the second n-well;

a second layer of gate oxide above said first n- well:

a second polysilicon floating gate above said second layer of gate oxide, the second polysilicon floating gate connected to the first polysilicon floating gate; and

a conductor connecting the second drain and the second source, a number of electrons removed from the second polysilicon floating gate increased responsive to increase in voltage at the second drain or the second source.

----

a third p+ doped region and a fourth p+ doped region disposed in said second n- well, said third p+ region and said fourth p+ region together forming a tunneling junction;

a layer of gate oxide disposed above said channel, said first n-well and said second nwell;

a polysilicon floating gate disposed above said layer of gate oxide; a source contact terminal electrically coupled to said source; a drain contact terminal electrically coupled to said drain; and a well contact terminal electrically coupled to said second n well.

49. (Currently amended) [[A]] p-channel floating gate device in accordance with claim
48, wherein the second drain comprises a said third p+ doped region within the second n-well, the second source comprises a and said fourth p+ doped region, wherein the conductor

<u>comprises\_are shorted together with a conductive layer which forms a bridge over said second polysilicon floating gate.</u>

- 50. (Canceled)
- 51. (Currently amended) [[A]] <u>The p-channel floating gate device in accordance with claim 48 elaim 50</u>, wherein said <u>readout transistor and the shorted transistor include transistor is formed with a single layer of conductive polysilicon.</u>
- 52. (Currently amended) [[A]] <u>The p-channel floating gate device in accordance with claim 48, wherein the floating gate device is fabricated using a standard CMOS process.</u>